



MEMC 98-4650(2293)  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Gregory Michael Wilson et al.

Art Unit 1765

Serial No. 09/608,302

Filed June 30, 2000

Confirmation No. 9819

For A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A  
DENUDED ZONE

Examiner Robert M. Kunemund

May 14, 2004

**NOTICE OF APPEAL FROM THE PRIMARY EXAMINER  
TO THE BOARD OF PATENT APPEALS AND INTERFERENCES**

COMMISSIONER FOR PATENTS  
P.O. BOX 1450  
ALEXANDRIA, VIRGINIA 22313-1450

SIR:

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the decision of the Examiner dated January 14, 2004, rejecting the following claims: 1-3, 9, 12 and 15-17.

The Commissioner is hereby authorized to charge Deposit Account No. 19-1345 in the amount of \$440.00 (\$330.00 for the appeal fee and \$110.00 for a one month extension of time under 37 CFR 1.136(a)). If there are any additional charges in this matter, please charge our Deposit Account No. 19-1345.

05/18/2004 HDEMESS1 00000110 09608302

01 FC:1401

330.00 0P

05/18/2004 HDEMESS1 00000110 09608302

02 FC:1251

110.00 0P

Respectfully submitted,

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